

FIG. 1

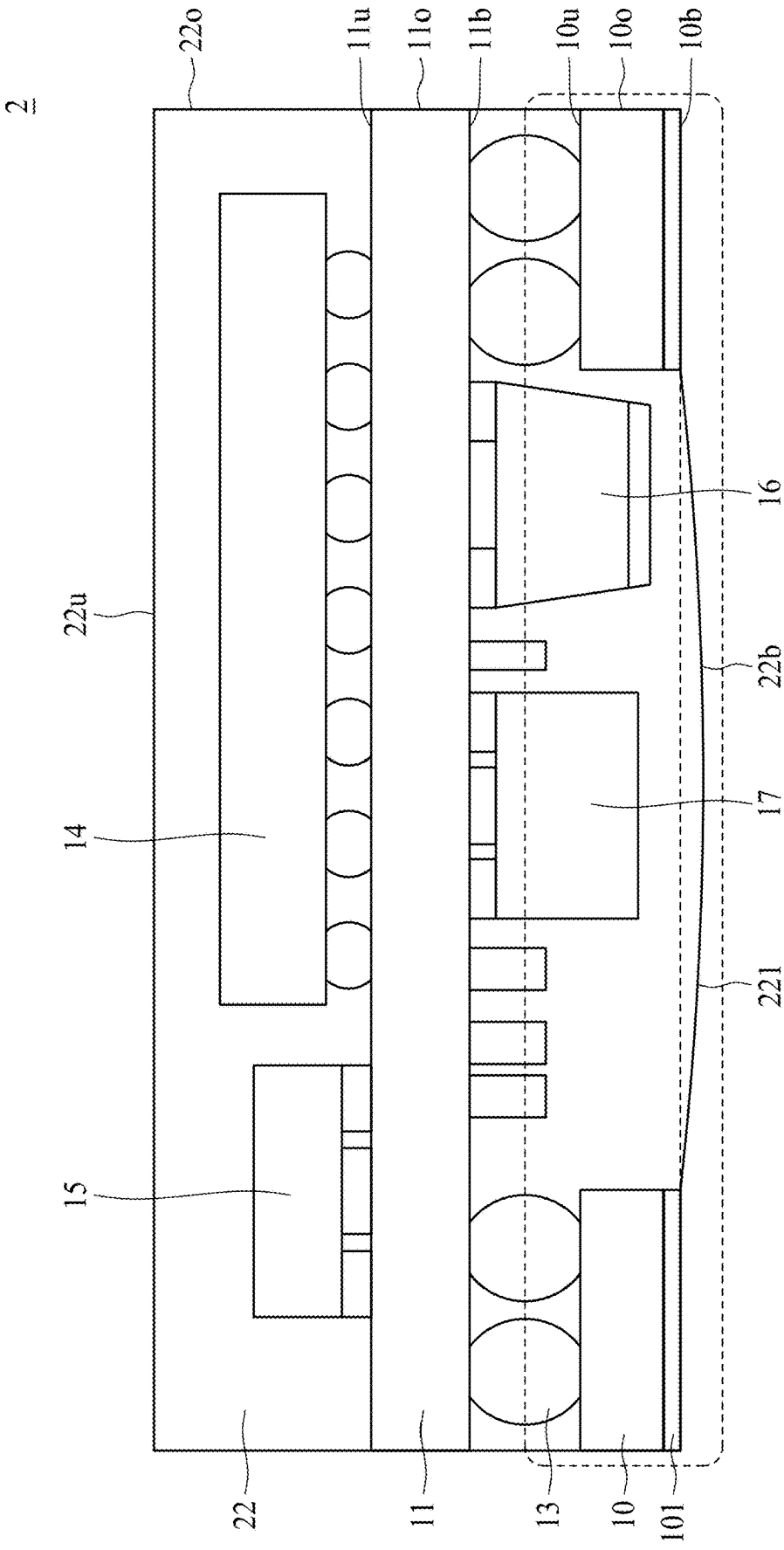


FIG. 2A

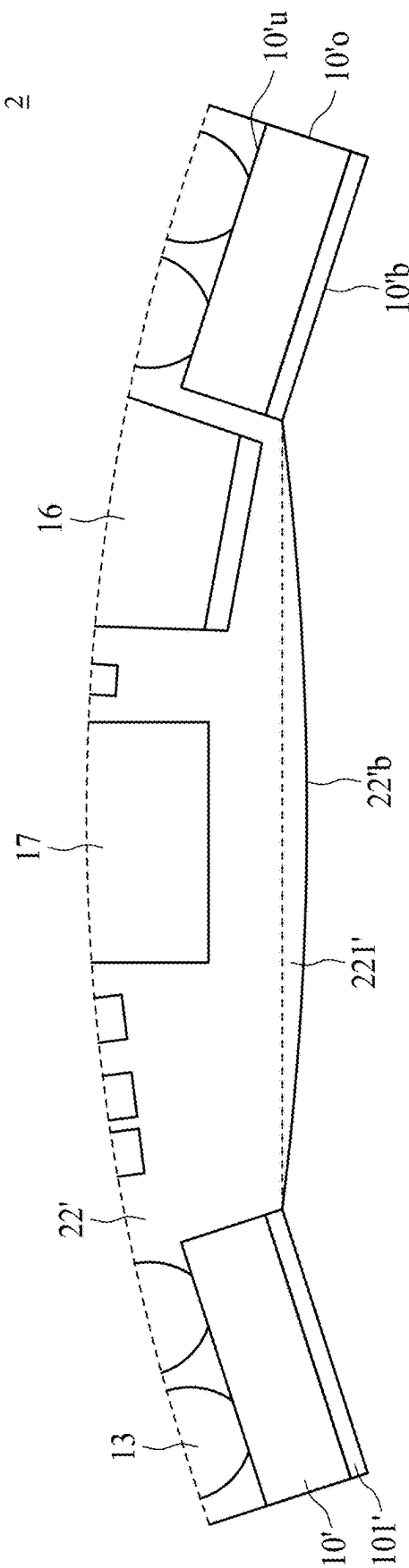


FIG. 2B

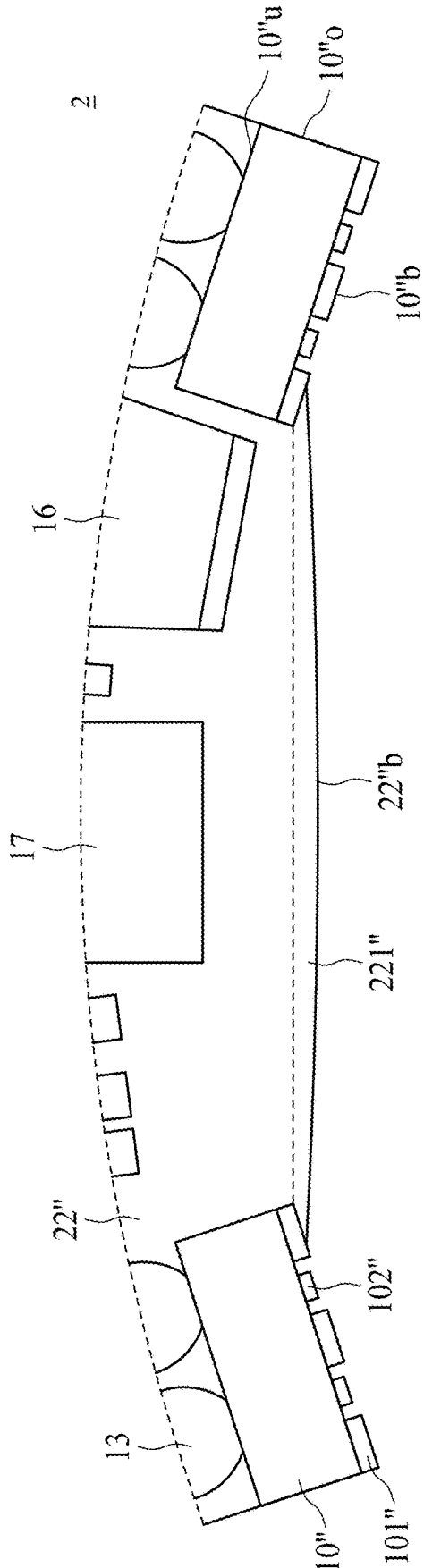


FIG. 2C

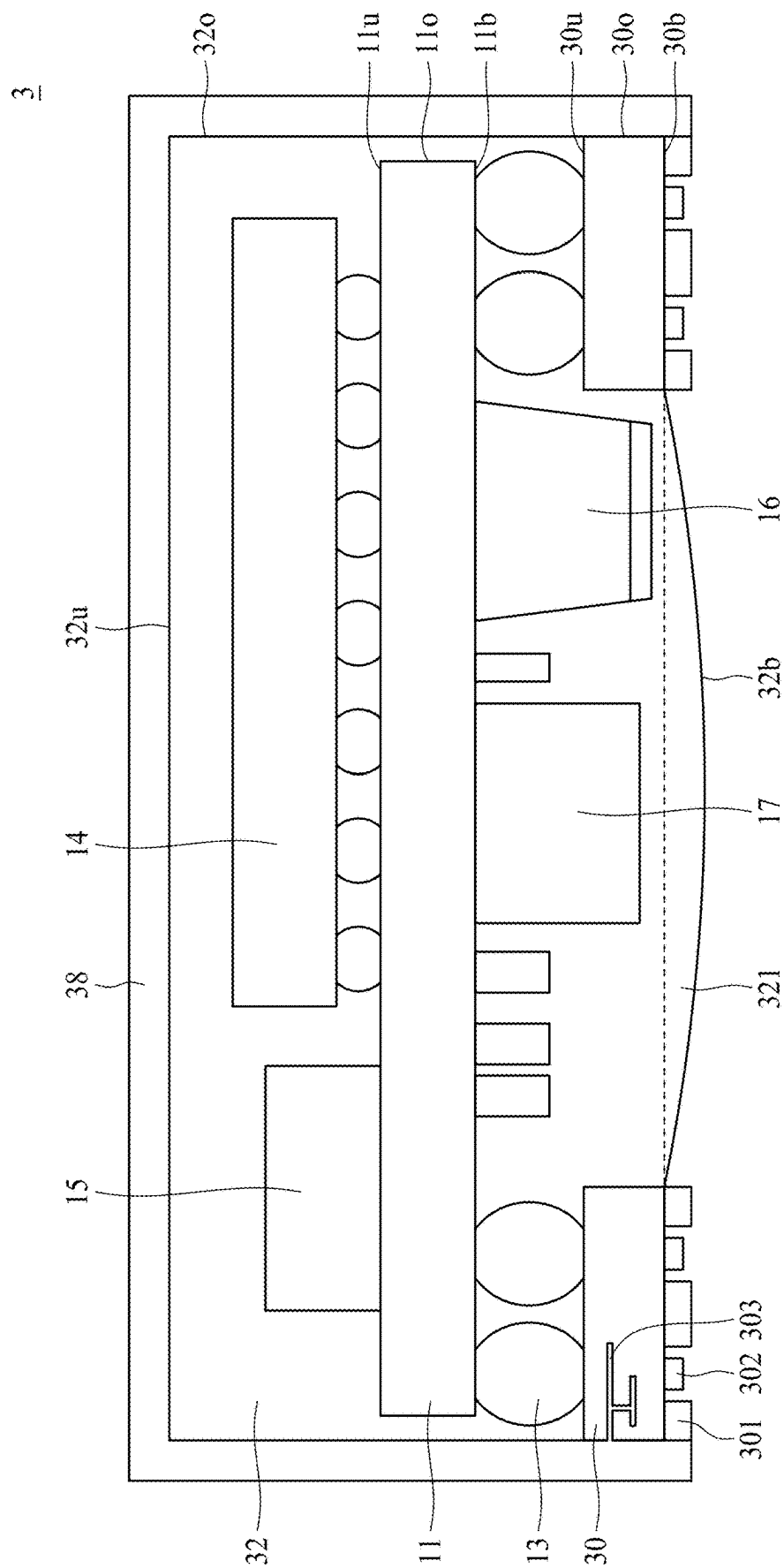


FIG. 3A

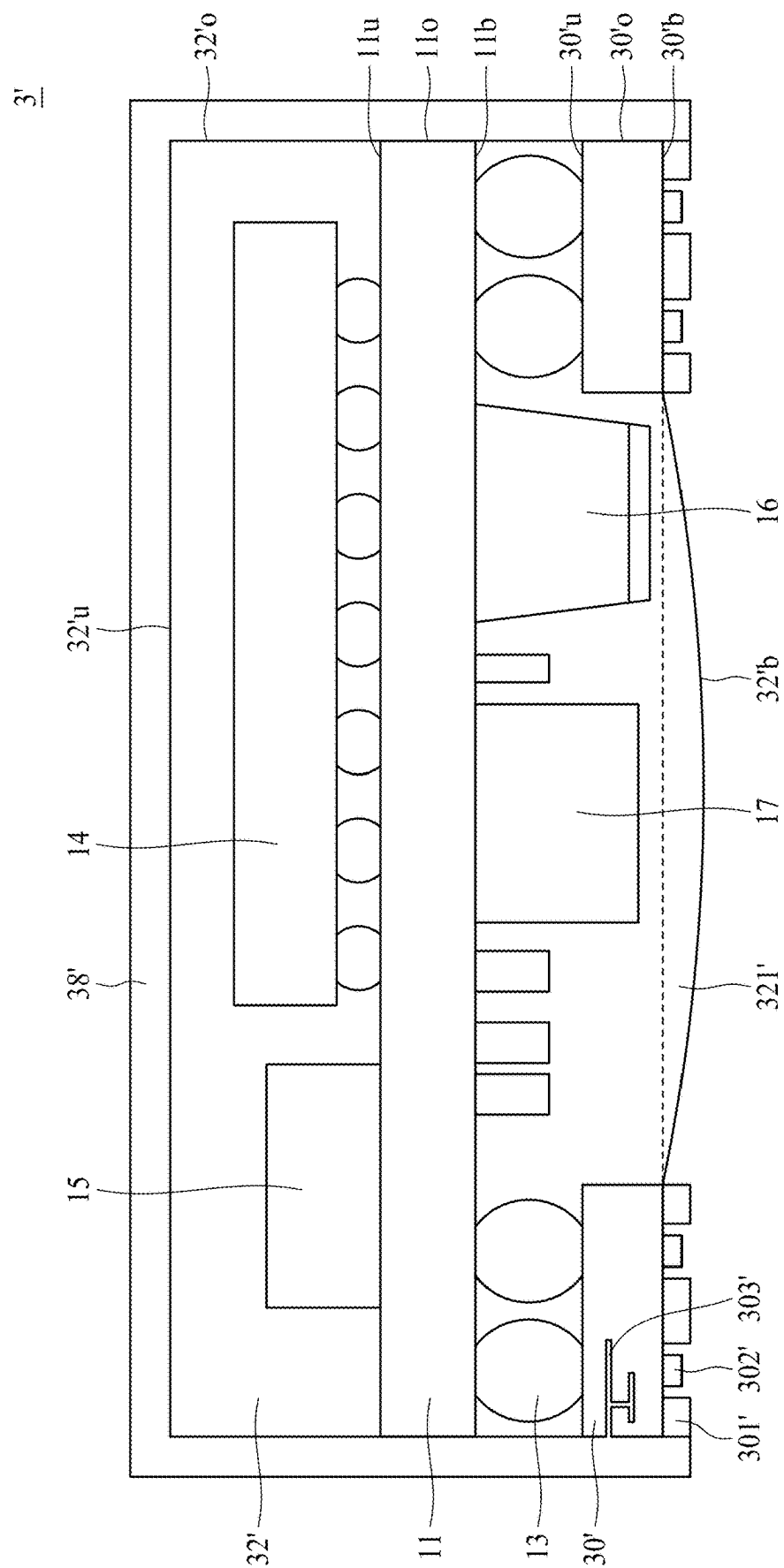
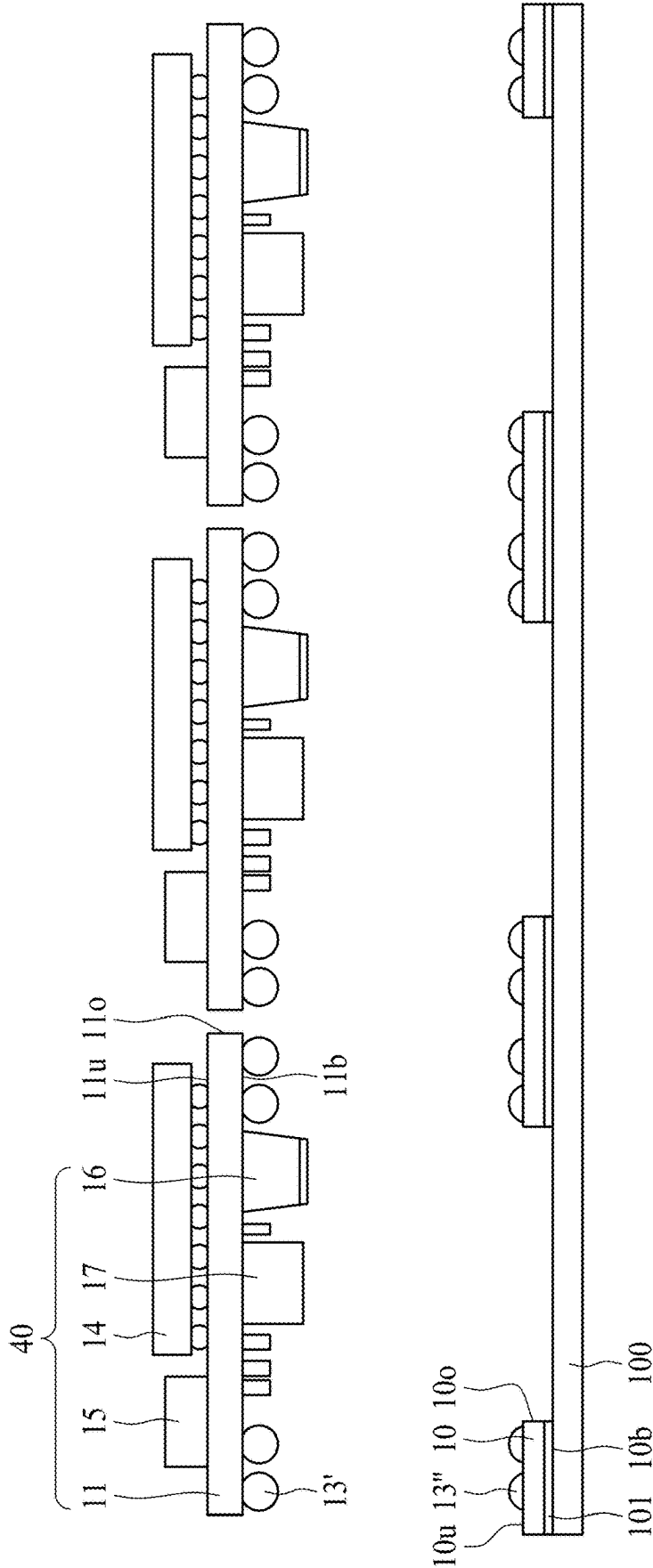


FIG. 3B



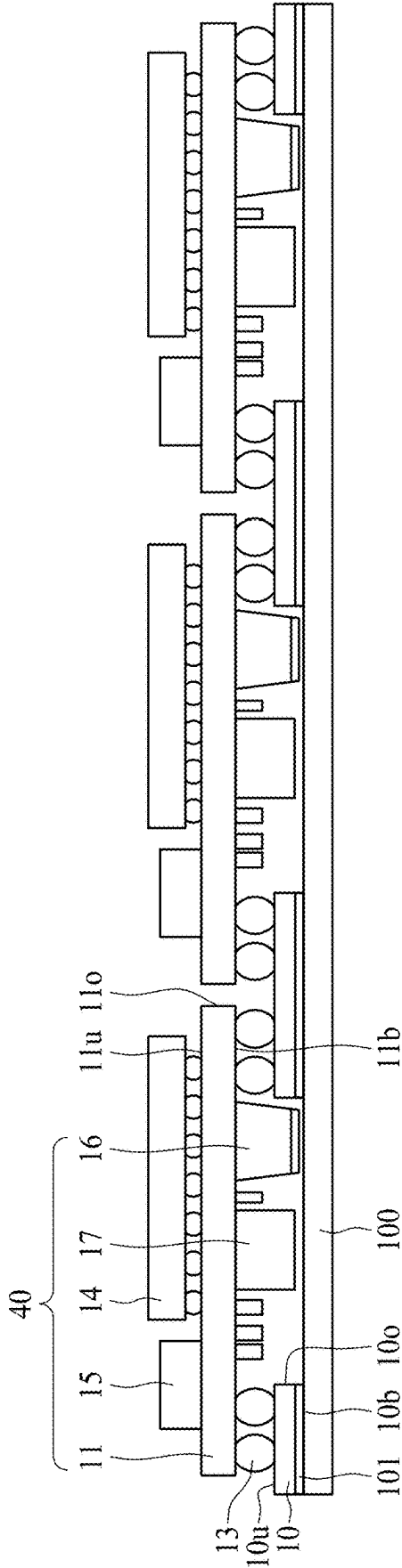


FIG. 4B

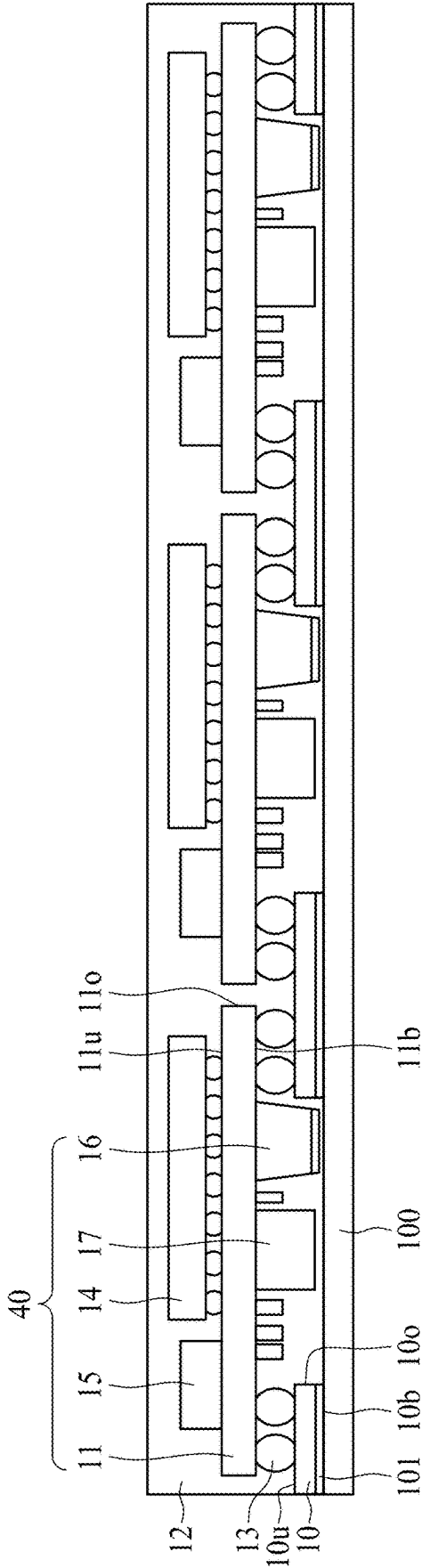


FIG. 4C



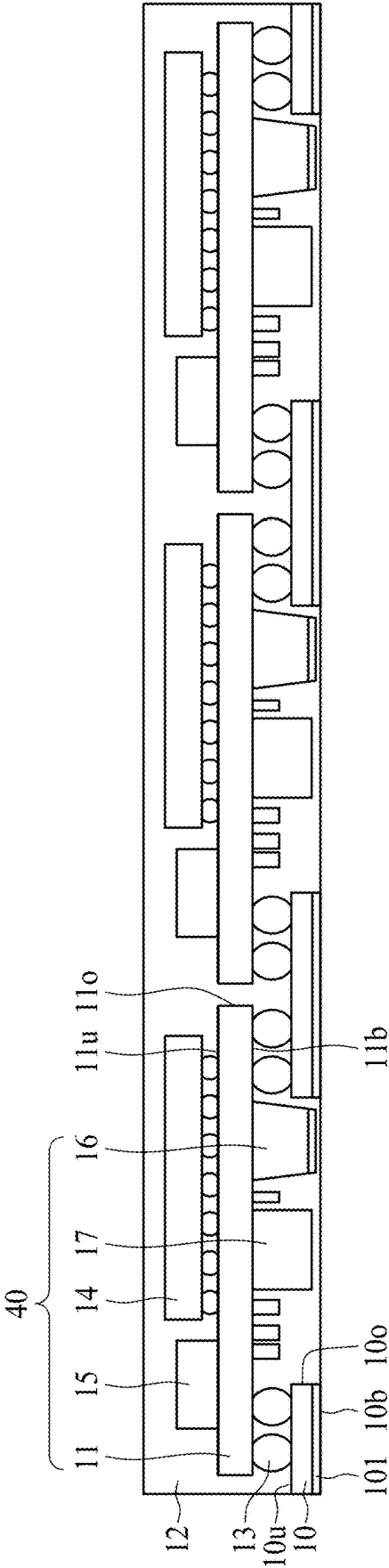


FIG. 4D

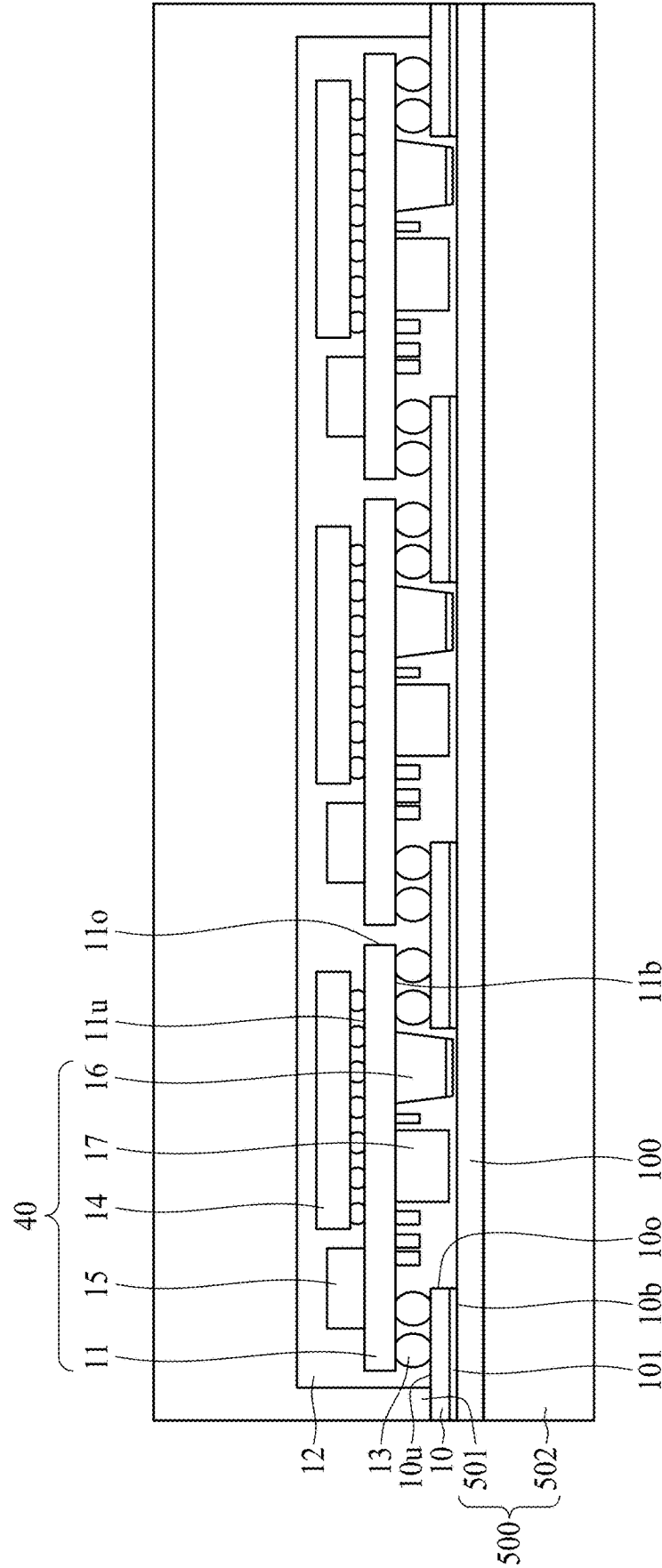


FIG. 5



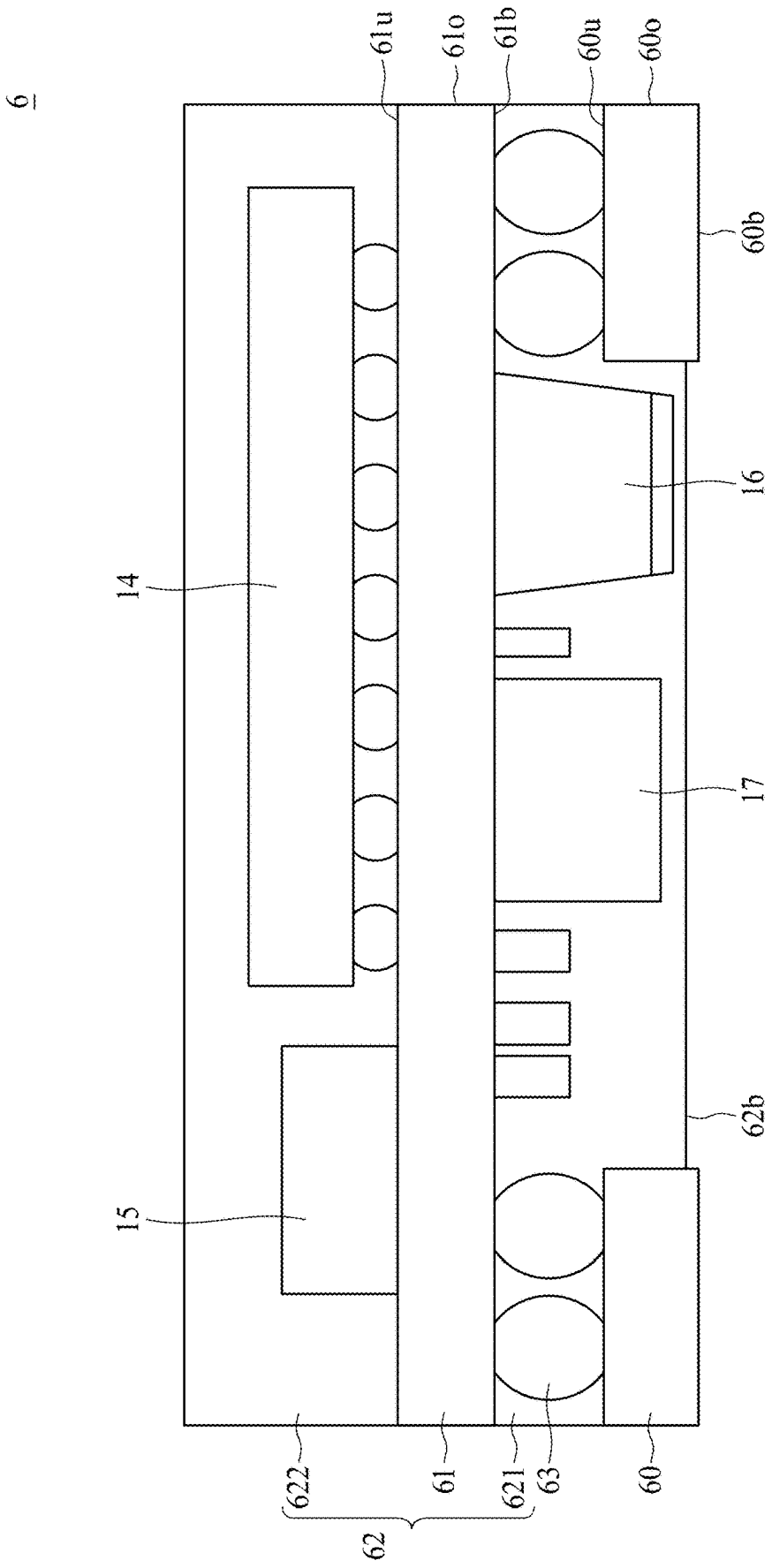


FIG. 7

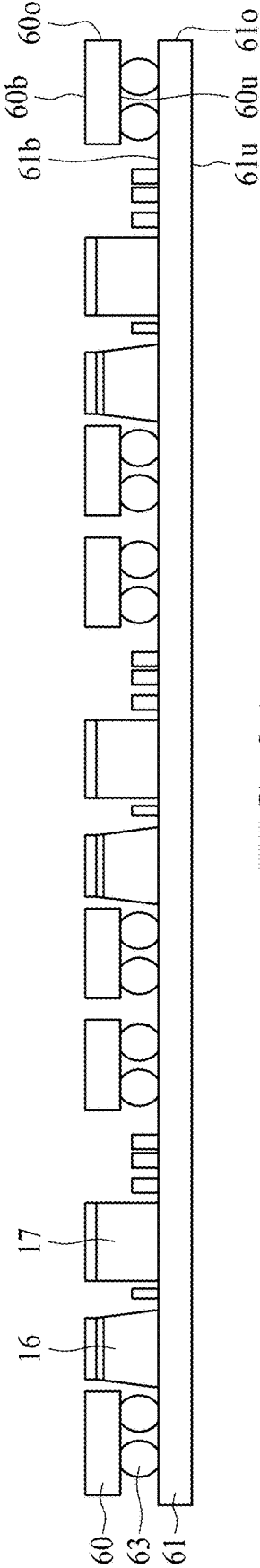


FIG. 8A

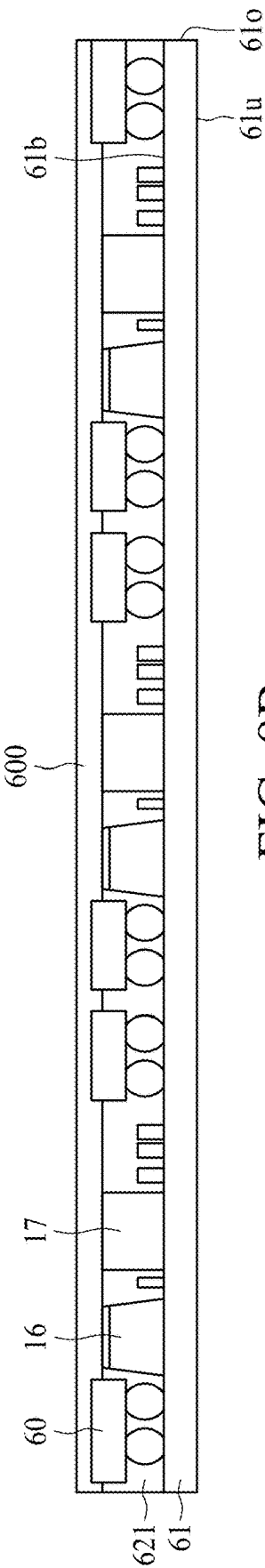


FIG. 8B

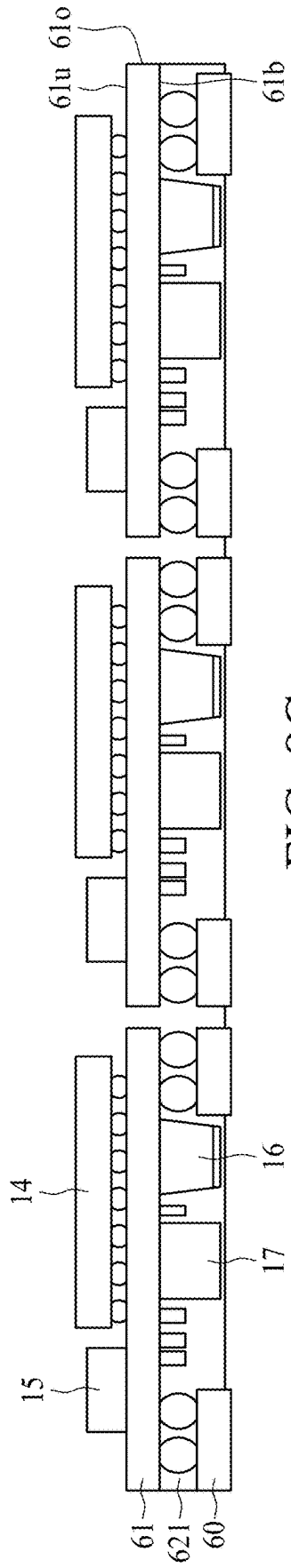


FIG. 8C

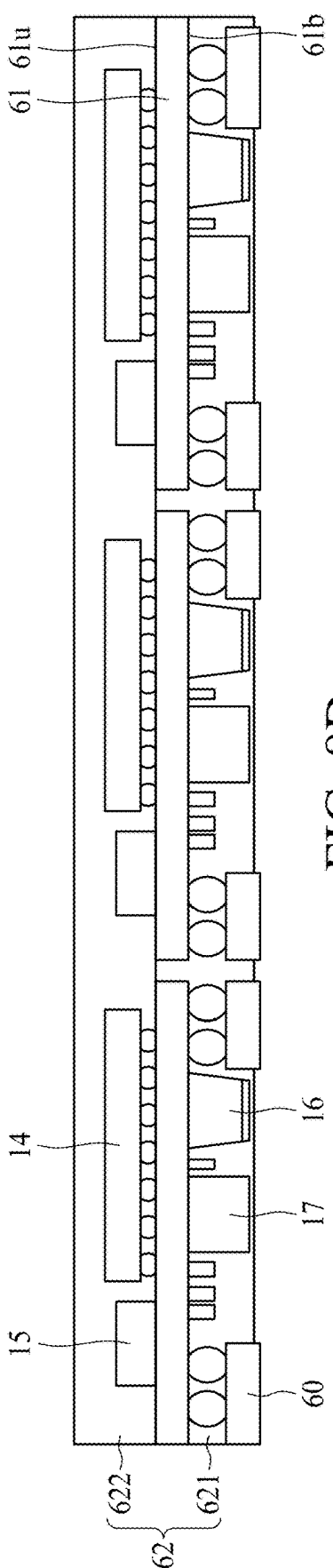


FIG. 8D

## SEMICONDUCTOR DEVICE PACKAGE AND A METHOD OF MANUFACTURING THE SAME

### CROSS-REFERENCE TO RELATED APPLICATION

[0001] This application is a continuation of U.S. patent application Ser. No. 18/112,463 filed Feb. 21, 2023, now issued as U.S. Pat. No. 12,283,569, which is a continuation of U.S. patent application Ser. No. 15/960,416 filed Apr. 23, 2018, now issued as U.S. Pat. No. 11,587,903, the contents of which is incorporated herein by reference in its entirety.

### BACKGROUND

#### 1. Technical Field

[0002] The present disclosure relates to a semiconductor device package including a first substrate, a second substrate, and an encapsulant.

#### 2. Description of the Related Art

[0003] To improve performance of a semiconductor device package, electronic components or semiconductor devices can be disposed on both sides of a substrate. A frame board, which may surround some components or semiconductor devices, is disposed on the substrate via connection elements (e.g. solder bumps). A multi-side molding technique may be used to encapsulate components or semiconductor devices on both sides of the substrate. Such a multi-side molding technique may involve two molding operations. During the molding operations, the connection elements to connect the frame board to the substrate may be deformed or damaged, which may adversely affect the performance of the semiconductor device package.

### SUMMARY

[0004] In some embodiments, according to one aspect, a semiconductor device package includes a first substrate with a first surface and a second surface opposite to the first surface, a second substrate adjacent to the first surface of the first substrate, and an encapsulant encapsulating the first substrate and the second substrate. The first substrate defines a space. The second substrate covers the space. The second surface of the first substrate is exposed by the encapsulant. A surface of the encapsulant is coplanar with the second surface of the first substrate or protrudes beyond the second surface of the first substrate.

[0005] In some embodiments, according to another aspect, a semiconductor device package includes a first substrate with a surface, a second substrate adjacent to the first substrate, an encapsulant encapsulating the second substrate, and a conductive layer disposed on the encapsulant and the surface of the first substrate. The first substrate includes a grounding layer exposed from the surface. The first substrate defines a space. The second substrate covers the space. The encapsulant fills the space. The conductive layer is in contact with the grounding layer.

[0006] In some embodiments, according to another aspect, a semiconductor device package includes a first substrate defining a space, a second substrate adjacent to the first substrate and covering the space, a first electronic component, a second electronic component, and an encapsulant. The second substrate has a first surface, a second surface

opposite to the first surface and a third surface extending from the first surface to the second surface. The first electronic component is disposed on the first surface of the second substrate. The second electronic component is disposed on the second surface of the second substrate and in the space of the first substrate. The encapsulant has a surface and encapsulates the first substrate, the second substrate, the first electronic component, and the second electronic component. The third surface of the second substrate is offset from the surface of the encapsulant by a non-zero distance.

[0007] In some embodiments, according to another aspect, a method for manufacturing a semiconductor device package includes: providing a first substrate with a first surface and a second surface opposite to the first surface, the first substrate defining a plurality of spaces; disposing an adhesive layer on the second surface of the first substrate; providing a semiconductor device module on the first surface of the first substrate; and encapsulating the first substrate and the semiconductor device module with an encapsulant.

### BRIEF DESCRIPTION OF THE DRAWINGS

[0008] FIG. 1 illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0009] FIG. 2A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0010] FIG. 2B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0011] FIG. 2C illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0012] FIG. 3A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0013] FIG. 3B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0014] FIG. 4A illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0015] FIG. 4B illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0016] FIG. 4C illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0017] FIG. 4D illustrates a method of manufacturing a semiconductor device package according to some embodiments of the present disclosure.

[0018] FIG. 5 illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0019] FIG. 6A illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0020] FIG. 6B illustrates a cross-sectional view of a semiconductor device package according to some embodiments of the present disclosure.

[0021] FIG. 7 illustrates a cross-sectional view of a comparative semiconductor device package.

[0022] FIG. 8A illustrates a method of manufacturing a comparative semiconductor device package.

[0023] FIG. 8B illustrates a method of manufacturing a comparative semiconductor device package.

[0024] FIG. 8C illustrates a method of manufacturing a comparative semiconductor device package.

[0025] FIG. 8D illustrates a method of manufacturing a comparative semiconductor device package.

#### DETAILED DESCRIPTION

[0026] Common reference numerals are used throughout the drawings and the detailed description to indicate the same or similar components. Embodiments of the present disclosure will be readily understood from the following detailed description taken in conjunction with the accompanying drawings.

[0027] Spatial descriptions, such as “above,” “below,” “up,” “left,” “right,” “down,” “top,” “bottom,” “vertical,” “horizontal,” “side,” “higher,” “lower,” “upper,” “over,” “under,” and so forth, are specified with respect to a certain component or group of components, or a certain plane of a component or group of components, for the orientation of the component(s) as shown in the associated figure. It should be understood that the spatial descriptions used herein are for purposes of illustration only, and that practical implementations of the structures described herein can be spatially arranged in any orientation or manner, provided that the merits of embodiments of this disclosure are not deviated from by such arrangement.

[0028] FIG. 1 is a cross-sectional view of a semiconductor device package 1 in accordance with some embodiments of the present disclosure. The semiconductor device package 1 includes a substrate 10, a substrate 11, an encapsulant 12, a connection element 13, and electronic components (e.g. semiconductor devices) 14, 15, 16, 17.

[0029] The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface 11b. The outer surface 110 of the substrate 11 extends from the upper surface 11u to the lower surface 11b. In some embodiments, the substrate 11 may include a main board. The electronic components 14 and 15 are disposed on the upper surface 11u of the substrate 11. The electronic components 16 and 17 are disposed on the lower surface 11b of the substrate 11. The electronic components 14, 15, 16, or 17 may constitute at least a portion of a flip chip package, a wire-bond package, or both. The electronic components 14, 15, 16, and 17 may be passive devices (including, for example, a capacitor) and/or active devices (including, for example, a semiconductor die).

[0030] The substrate 10 has an upper surface 10u, an outer/lateral surface 100, and a lower surface 10b. The outer surface 100 of the substrate 10 extends from the upper surface 10u to the lower surface 10b. The outer surface 100 of the substrate 10 and the outer surface 110 of the substrate 11 are coplanar. In some embodiments, the substrate 10 may include a frame board. The substrate 10 may include a dielectric layer 101. The substrate 10 may include a conductive pad surrounded by the dielectric layer 101. In some embodiments, the dielectric layer 101 may be a solder resist layer. The dielectric layer 101 may be omitted. The substrate 10 is adjacent to the substrate 11. The substrate 10 is electrically connected to the substrate 11 via the connection element 13. The connection element 13 may be a solder bump. The substrate 10 defines a space (or an opening) or a

plurality of spaces (or a plurality of openings). The electronic components 16 and 17 are disposed at least partially in the space of the substrate 10. The substrate 11 covers the space.

[0031] The encapsulant 12 (which may include a molding compound) has an upper surface 12u, an outer/lateral surface 120, and a lower surface 12b. The outer surface 120 of the encapsulant 12 may extend from the upper surface 12u to the lower surface 12b (e.g. may extend around a side of the substrate 11, not shown). The encapsulant 12 encapsulates the substrate 10 and the substrate 11. The encapsulant 12 encapsulates the electronic components 14, 15, 16, 17. The outer surface 100 of the substrate 10, the outer surface 110 of the substrate 11, and the outer surface 120 of the encapsulant 12 are coplanar. The lower surface 10b of the substrate 10 and the lower surface 12b of the encapsulant 12 are coplanar. The lower surface 10b of the substrate 10 is exposed by the encapsulant 12. In some embodiments, the encapsulant 12 may completely encapsulate the substrate 11. In such an embodiment, the outer surface 110 of the substrate 11 may be completely covered by the encapsulant 12.

[0032] FIG. 2A is a cross-sectional view of a semiconductor device package 2 in accordance with some embodiments of the present disclosure. The semiconductor device package 2 includes a substrate 10, a substrate 11, an encapsulant 22, a connection element 13, and electronic components 14, 15, 16, 17.

[0033] The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface 11b. The outer surface 110 of the substrate 11 extends from the upper surface 11u to the lower surface 11b. In some embodiments, the substrate 11 includes a main board. The electronic components 14 and 15 are disposed on the upper surface 11u of the substrate 11. The electronic components 16 and 17 are disposed on the lower surface 11b of the substrate 11.

[0034] The substrate 10 has an upper surface 10u, an outer/lateral surface 100, and a lower surface 10b. The outer surface 100 of the substrate 10 extends from the upper surface 10u to the lower surface 10b. The outer surface 100 of the substrate 10 and the outer surface 110 of the substrate 11 are coplanar. The substrate 10 may include a dielectric layer 101. The dielectric layer 101 is adjacent to the lower surface 10b. The substrate 10 may include a conductive pad surrounded by the dielectric layer 101. In some embodiments, the dielectric layer 101 may be a solder resist layer. The dielectric layer 101 may be omitted. The substrate 10 is adjacent to the substrate 11. The substrate 10 is electrically connected to the substrate 11 via the connection element 13. The substrate 10 defines a space. The electronic components 16 and 17 are disposed in the space of the substrate 10. The substrate 11 covers the space. The substrate 10 extends horizontally.

[0035] The encapsulant 22 has an upper surface 22u, an outer/lateral surface 220, and a lower surface 22b. The outer surface 220 of the encapsulant 22 may extend from the upper surface 22u to the lower surface 22b (e.g. may extend around a side of the substrate 11, not shown). The encapsulant 22 encapsulates the substrate 10 and the substrate 11. The encapsulant 22 encapsulates the electronic components 14, 15, 16, 17. The outer surface 100 of the substrate 10, the outer surface 110 of the substrate 11, and the outer surface 220 of the encapsulant 22 are coplanar. The lower surface 10b of the substrate 10 is exposed by the encapsulant 22. In some embodiments, the encapsulant 22 may completely



encapsulate the substrate 11. In such an embodiment, the outer surface 110 of the substrate 11 may be completely covered by the encapsulant 22.

[0036] The encapsulant 22 includes a portion 221. The portion 221 protrudes below (or beyond) the substrate 10. The portion 221 protrudes below the dielectric layer 101 of the substrate 10. The lower surface 22b of the encapsulant 22 is a surface of the portion 221 and protrudes below the surface 10b of the substrate 10. The encapsulant 22 may substantially fill the space defined by the substrate 10.

[0037] FIG. 2B is a cross-sectional view of a semiconductor device package 2 including a substrate 10' and an encapsulant 22' in accordance with some embodiments of the present disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. 2A.

[0038] The substrate 10' has an upper surface 10'u, an outer/lateral surface 10'o, and a lower surface 10'b. The substrate 10' includes a dielectric layer 101'. The dielectric layer 101' may be a solder resist layer. The substrate 10' defines a space. Electronic components 16 and 17 are disposed in the space of the substrate 10'.

[0039] The substrate 10' is slightly inclined (e.g. relative to a central portion of the semiconductor device package 2, and/or relative to a centrally located electronic component, such as the electronic component 17). A central portion of the substrate 10' is higher than a peripheral portion of the substrate 10' (e.g. the central portion of the substrate 10' is closer to the substrate 11 than is a peripheral portion of the substrate 10'). An inner lateral surface of the substrate 10' may be higher than the outer lateral surface 10'o. The substrate 10' is encapsulated by the encapsulant 22'. The encapsulant 22' includes a portion 221' having a lower surface 22'b. The portion 221' protrudes below at least a portion of the substrate 10'. The portion 221' protrudes below at least a portion of the dielectric layer 101' of the substrate 10'. The lower surface 22'b of the portion 221' protrudes below at least a portion of the surface 10'b of the substrate 10'. A central portion of the lower surface 22'b may protrude further than does an outer portion of the lower surface 22'b.

[0040] FIG. 2C is a cross-sectional view of the semiconductor device package 2 including a substrate 10'' and an encapsulant 22'' in accordance with some embodiments of the present disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. 2A.

[0041] The substrate 10'' has an upper surface 10''u, an outer/lateral surface 10''o, and a lower surface 10''b. The substrate 10'' includes a dielectric layer 101'' and a conductive pad 102''. The dielectric layer 101'' may be a solder resist layer. The dielectric layer 101'' surrounds the conductive pad 102''. The substrate 10'' defines a space. Electronic components 16 and 17 are disposed in the space of the substrate 10''.

[0042] The substrate 10'' is slightly inclined (e.g. relative to a central portion of the semiconductor device package 2, and/or relative to a centrally located electronic component, such as the electronic component 17). A central portion of the substrate 10'' is higher than a peripheral portion of the substrate 10'' (e.g. the central portion of the substrate 10'' is closer to the substrate 11 than is a peripheral portion of the substrate 10''). An inner lateral surface of the substrate 10'' may be higher than the outer lateral surface 10''o. The substrate 10'' is encapsulated by the encapsulant 22''. The encapsulant 22'' includes a portion 221'' having a lower

surface 22''b. The portion 221'' protrudes below at least a portion of the substrate 10''. The portion 221'' protrudes below at least a portion of the dielectric layer 101'' of the substrate 10''. The lower surface 22''b of the portion 221'' protrudes below at least a portion of the surface 10''b of the substrate 10''. The portion 221'' covers a portion of the substrate 10''. The portion 221'' partially covers the lower surface 10''b of the substrate 10''. The portion 221'' partially covers a portion of the dielectric layer 101''. The portion 221'' and the conductive pad 102'' on the substrate 10'' are spaced by a distance. In some embodiments (not shown), a central portion of the lower surface 22''b may protrude further than does an outer portion of the lower surface 22''b.

[0043] FIG. 3A is a cross-sectional view of a semiconductor device package 3 in accordance with some embodiments of the present disclosure. The semiconductor device package 3 includes a substrate 30, a substrate 11, an encapsulant 32, a connection element 13, electronic components 14, 15, 16, 17, and a conductive layer 38.

[0044] The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface 11b. The outer surface 110 of the substrate 11 extends from the upper surface 11u to the lower surface 11b. In some embodiments, the substrate 11 may include a main board. The electronic components 14 and 15 are disposed on the upper surface 11u of the substrate 11. The electronic components 16 and 17 are disposed on the lower surface 11b of the substrate 11.

[0045] The substrate 30 has an upper surface 30u, an outer/lateral surface 300, and a lower surface 30b. The outer surface 300 of the substrate 30 extends from the upper surface 30u to the lower surface 30b. The outer surface 300 of the substrate 30 and the outer surface 110 of the substrate 11 (which are substantially parallel to one another) are offset from each other, and are not coplanar. In some embodiments, the substrate 30 may include a frame board. The substrate 30 may include a dielectric layer 301, a conductive pad 302, and a conductive layer 303. In some embodiments, the conductive pad 302 may be replaced with a solder bump. The conductive pad 302 is surrounded by the dielectric layer 301. In some embodiments, the dielectric layer 301 may be a solder resist layer. The dielectric layer 301 may be omitted. The conductive layer 303 may be a grounding layer. The conductive layer 303 is exposed from the outer surface 300. The substrate 30 is adjacent to the substrate 11. The substrate 30 is electrically connected to the substrate 11 via the connection element 13. The substrate 30 defines a space. The electronic components 16 and 17 are disposed in the space of the substrate 30. The substrate 11 covers the space.

[0046] The encapsulant 32 has an upper surface 32u, an outer/lateral surface 320, and a lower surface 32b. The encapsulant 32 encapsulates the substrate 30 and the substrate 11. The encapsulant 32 encapsulates the electronic components 14, 15, 16, 17. The outer surface 300 of the substrate 30 and the outer surface 320 of the encapsulant 32 are coplanar. The lower surface 30b of the substrate 30 is exposed by the encapsulant 32. The encapsulant 32 completely encapsulates the substrate 11. The outer surface 110 of the substrate 11 is completely covered by the encapsulant 32. The outer surface 110 of the substrate 11 is spaced from the outer surface 320 of the encapsulant 32 by a non-zero distance. The outer surface 110 of the substrate 11 and the outer surface 320 of the encapsulant 32 (which are substantially parallel to one another) are offset from each other, and are not coplanar.

[0047] The encapsulant 32 includes a portion 321. The portion 321 protrudes below the substrate 30. The portion 321 protrudes below the dielectric layer 301 of the substrate 30. The lower surface 32b of the portion 321 protrudes below the surface 30b of the substrate 30.

[0048] The conductive layer 38 is disposed on the encapsulant 32 and the outer surface 300 of the substrate 30. The conductive layer 38 is in contact with the conductive layer 303. In some embodiments, the conductive layer 38 may be a shielding layer.

[0049] FIG. 3B is a cross-sectional view of a semiconductor device package 3' in accordance with some embodiments of the present disclosure. The semiconductor device package 3' includes a substrate 30', a substrate 11, an encapsulant 32', a connection element 13, electronic components 14, 15, 16, 17, and a conductive layer 38'.

[0050] The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface 11b. The outer surface 110 of the substrate 11 extends from the upper surface 11u to the lower surface 11b. In some embodiments, the substrate 11 may include a main board. The electronic components 14 and 15 are disposed on the upper surface 11u of the substrate 11. The electronic components 16 and 17 are disposed on the lower surface 11b of the substrate 11.

[0051] The substrate 30' has an upper surface 30'u, an outer/lateral surface 30'o, and a lower surface 30'b. The outer surface 30'o of the substrate 30' and the outer surface 110 of the substrate 11 are coplanar. In some embodiments, the substrate 30' may include a frame board. The substrate 30' may include a dielectric layer 301', a conductive pad 302', and a conductive layer 303'. The conductive pad 302' is surrounded by the dielectric layer 301'. In some embodiments, the dielectric layer 301' may be a solder resist layer. The dielectric layer 301' may be omitted. The conductive layer 303' may be a grounding layer. The conductive layer 303' is exposed from the outer surface 30'o. The substrate 30' is adjacent to the substrate 11. The substrate 30' is electrically connected to the substrate 11 via the connection element 13. The substrate 30' defines a space. The electronic components 16 and 17 are disposed in the space of the substrate 30'. The substrate 11 covers the space. In some embodiments, the substrate 11 may include a grounding layer exposed from the outer surface 110 of the substrate 11. The conductive layer 38' may contact the grounding layer of the substrate 11 and may be electrically connected to the connection element 13.

[0052] The encapsulant 32' has an upper surface 32'u, an outer/lateral surface 32'o, and a lower surface 32'b. The encapsulant 32' encapsulates the substrate 30' and the substrate 11. The encapsulant 32' encapsulates the electronic components 14, 15, 16, 17. The outer surface 30'o of the substrate 30' and the outer surface 32'o of the encapsulant 32' are coplanar. The lower surface 30'b of the substrate 30' is exposed by the encapsulant 32'.

[0053] The encapsulant 32' includes a portion 321'. The portion 321' protrudes below the substrate 30'. The portion 321' protrudes below the dielectric layer 301' of the substrate 30'. The lower surface 32'b of the portion 321' protrudes below the surface 30'b of the substrate 30'.

[0054] The conductive layer 38' is disposed on the encapsulant 32' and the outer surface 30'o of the substrate 30'. The conductive layer 38' is in contact with the conductive layer 303'. The conductive layer 38' is in contact with the outer

surface 110 of the substrate 11. In some embodiments, the conductive layer 38 may be a shielding layer.

[0055] FIG. 4A through FIG. 4D illustrate some embodiments of a method of manufacturing the semiconductor device package 1 according to some embodiments of the present disclosure. In some embodiments, a semiconductor device package 2 may be similarly manufactured by the depicted method.

[0056] Referring to FIG. 4A, a method for manufacturing the semiconductor device package 1 includes providing a substrate 10 with an upper surface 10u, an outer/lateral surface 100, and a lower surface 10b opposite to the surface 10u. The substrate 10 may include a frame board. The substrate 10 comprises a strip or a panel. The substrate 10 includes a dielectric layer 101. The substrate 10 may include a conductive pad surrounded by the dielectric layer 101. In some embodiments, the dielectric layer 101 may be a solder resist layer. A connection element 13" is disposed on the upper surface 10u of the substrate 10. The connection element 13" may include a solder material.

[0057] An adhesive layer 100 is disposed on the lower surface 10b of the substrate 10. An individual semiconductor device module 40 is disposed on the upper surface 10u of the substrate 10. The semiconductor device module 40 includes a substrate 11 and electronic components 14, 15, 16, and 17. The substrate 11 may include a main board. The substrate 11 has an upper surface 11u, an outer/lateral surface 110, and a lower surface 11b. Electronic components 14 and 15 are disposed on the upper surface 11u of the substrate 11. Electronic components 16 and 17 are disposed on the lower surface 11b of the substrate 11. A connection element 13' is disposed on the semiconductor device module 40. The connection element 13' may include a solder material.

[0058] In some embodiments, a strip or a panel of semiconductor device modules 40 is preprocessed by a singulation operation. The strip or a panel of semiconductor device modules 40 is divided into a plurality of units.

[0059] Referring to FIG. 4B, the semiconductor device module 40 is mounted on the substrate 10. The semiconductor device module 40 is electrically connected to the substrate 10 via a connection element 13 (e.g. a connection element formed from the connection element 13' and the connection element 13").

[0060] Referring to FIG. 4C, the substrate 10 and the semiconductor device module 40 is encapsulated by a one-time molding operation. The substrate 10 and the semiconductor device module 40 are encapsulated by an encapsulant 12. During the one-time molding operation, a carrier may be provided on the adhesive layer 100. The carrier covers the substrate 10, the adhesive layer 100, and the semiconductor device module 40. The carrier may be a mold chase. The one-time molding operation may significantly reduce costs of manufacturing of semiconductor device packages and increase throughputs (e.g. as compared to processes that involve more than a single molding operation).

[0061] Referring to FIG. 4D, the adhesive layer 100 is removed. Subsequently, a singulation operation is performed. During the singulation operation, the substrate 10 and the encapsulant 12 may be sawed. In some embodiments, the substrate 11 of the semiconductor device module 40 is sawed during the singulation operation.

[0062] FIG. 5 is a cross-sectional view of a semiconductor device package molded in a carrier 500 according to some embodiments of the present disclosure. The carrier 500 is

provided on the adhesive layer 100. The carrier 500 covers the substrate 10, the adhesive layer 100, and the semiconductor device module 40. The carrier 500 may be a mold chase.

[0063] The carrier 500 includes a portion 501 and a portion 502. The portion 501 presses on the substrate 10. The portion 502 presses on the adhesive layer 100. The substrate 10, the adhesive layer 100, and the semiconductor device module 40 are disposed between the portion 501 and the portion 502. The adhesive layer 100 is disposed between the substrate 10 and the portion 502. The portion 501 may not directly press or contact the semiconductor device module 40. The portion 501 may not directly press or contact the substrate 11 of the semiconductor device module 40. The substrate 10 and the semiconductor device module 40 are encapsulated in the carrier 500. Since the carrier 500 is disposed on the adhesive layer 100, the carrier 500 may directly press a periphery of the substrate 10 (e.g. on the surface 10u of the substrate 10), and may avoid directly pressing or contacting the substrate 11. This can help to ensure that the connection element 13 does not deform during the molding operation.

[0064] The semiconductor device package 1 or 2 may be manufactured using the carrier 500.

[0065] FIG. 6A is a cross-sectional view of a semiconductor device package molded in a carrier 500' according to some embodiments of the present disclosure. The carrier 500' is provided on an adhesive layer 100. The carrier 500' covers a substrate 10', the adhesive layer 100, and a semiconductor device module 40. The carrier 500' may be a mold chase.

[0066] The carrier 500' includes a portion 501 and a portion 502'. The portion 502' includes a protrusion 502'a (shown in FIG. 6B). The portion 501 presses on the substrate 10'. The portion 502' presses on the substrate 10' (e.g. via the adhesive layer 100). The substrate 10', the adhesive layer 100, and the semiconductor device module 40 are disposed between the portion 501 and the portion 502'. The adhesive layer 100 is disposed between the substrate 10' and the portion 502'. A space 503 is defined by two adjacent portions of the portion 502'. The space 503 is defined by the adhesive layer 100 and two adjacent portions of the portion 502'. The space 503 is located under the substrate 10'. The protrusion 502'a is located under an inner periphery of the substrate 10'. The protrusion 502'a correspondingly supports an inner peripheral portion of the substrate 10'. Since an injecting force of a molding operation may be very large, in some comparative implementations an injected encapsulant may flow or be pushed to a lower surface 10'b of the substrate 10' and may cover the lower surface 10'b (which may cause a disconnection issue). The design of the carrier 500' may help to prevent an encapsulant from flowing or being pushed to the lower surface 10'b of the substrate 10' and covering the lower surface 10'b.

[0067] FIG. 6B is a cross-sectional view of a carrier 500' according to some embodiments of the present disclosure, and shows an enlarged view of a region delimited by a dashed line in FIG. 6A. The protrusion 502'a of the carrier 500' supports an inner peripheral portion of the substrate 10', and may not fully support a central portion of the substrate 10'. Accordingly, the substrate 10' may slightly deform during the molding operation. The substrate 10' may be slightly inclined. A central portion of the substrate 10' may be higher than a peripheral portion of the substrate 10'.

[0068] A surface 502'u of the portion 502' and a lower surface of the adhesive layer 100 are spaced by a distance D1. The distance D1 is in a range from approximately 0.01 millimeters (mm) to approximately 0.02 mm. An outer surface of the protrusion 502'a and an inner surface of the substrate 10' are offset by a distance D2. The distance D2 is in a range from approximately 0.2 mm to approximately 0.25 mm.

[0069] According to the design of the carrier 500', the substrates 10' and 10'' of FIG. 2B and FIG. 2C may be manufactured.

[0070] FIG. 7 is a cross-sectional view of a comparative semiconductor device package 6. The semiconductor device package 6 includes a substrate 60, a substrate 61, an encapsulant 62, a connection element 63, and electronic components 14, 15, 16, 17.

[0071] The substrate 61 has an upper surface 61u, an outer/lateral surface 610, and a lower surface 61b. The substrate 11 includes a main board. The electronic components 14 and 15 are disposed on the upper surface 61u of the substrate 61. The electronic components 16 and 17 are disposed on the lower surface 61b of the substrate 61.

[0072] The substrate 60 has an upper surface 60u, an outer/lateral surface 600, and a lower surface 60b. The substrate 60 may include a frame board. The substrate 60 may include a solder resist layer and a conductive pad. The conductive pad is surrounded by the solder resist layer. The substrate 60 is adjacent to the substrate 61. The substrate 60 is electrically connected to the substrate 61 via the connection element 63. The connection element 63 is a solder bump. The substrate 60 defines a space. The electronic components 16 and 17 are disposed in the space of the substrate 60. The substrate 61 covers the space.

[0073] The encapsulant 62 has an upper surface 62u, an outer/lateral surface 620, and a lower surface 62b. The encapsulant includes a portion 621 and a portion 622. The encapsulant 62 encapsulates the substrate 60 and the substrate 61. The encapsulant 12 encapsulates the electronic components 14, 15, 16, 17. The lower surface 60b of the substrate 10 is lower than the lower surface 62b of the encapsulant 62. The lower surface 60b of the substrate 60 is exposed by the encapsulant 62. Part of an inner peripheral surface of the substrate 60 is exposed by the encapsulant 62.

[0074] FIG. 8A through FIG. 8D illustrate some embodiments of a method of manufacturing the semiconductor device package 6.

[0075] Referring to FIG. 8A, a method for manufacturing the semiconductor device package 6 includes providing a substrate 61 with an upper surface 61u, an outer/lateral surface 610, and a lower surface 61b opposite to the surface 61u. The substrate 61 comprises a strip or a panel. A substrate 60 is provided on the substrate 61. The substrate 60 has an upper surface 60u, an outer/lateral surface 600, and a lower surface 60b opposite to the surface 60u. The substrate 60 is mounted on the lower surface 61b of the substrate 61 via the connection element 63. The substrate 60 comprises a strip or a panel. Electronic components 16 and 17 are disposed on the lower surface 61b of the substrate 61.

[0076] Referring to FIG. 8B, an adhesive layer 600 is provided on the substrate 60 and subsequently, a first molding operation is performed. During the first molding operation, a mold chase may directly press the substrate 61 and the adhesive layer 600. The substrate 60, the substrate 61, and the electronic components 16 and 17 are encapsulated by an

encapsulant **621**. Since the mold chase would directly press the substrate **61** and the adhesive layer **600** during the first molding operation, the lower surface **60b** of the substrate **60** and a lower surface of encapsulant **621** are not coplanar.

[0077] Furthermore, since the substrate **61** is pressed by the mold chase, the connection element **63** may deform by the pressure from the mold chase. The deformation of the connection element **63** may cause a delamination between the connection element **63** and the encapsulant **621**.

[0078] Referring to FIG. 8C, electronic components **14** and **15** are disposed on the upper surface **61u** of the substrate **61**. The adhesive layer **600** is removed.

[0079] Referring to FIG. 8D, a second molding operation is performed. The substrate **61** and the electronic components **14** and **15** are encapsulated by an encapsulant **622**. An encapsulant **62** including the encapsulant **621** and the encapsulant **622** encapsulates the substrate **60**, the substrate **61**, and the electronic components **14**, **15**, **16**, and **17**. Subsequently, a singulation operation is performed. The lower surface **60b** of the substrate **10** is higher than a lower surface of the encapsulant **62**.

[0080] As used herein and not otherwise defined, the terms “substantially,” “substantial,” “approximately” and “about” are used to describe and account for small variations. When used in conjunction with an event or circumstance, the terms can encompass instances in which the event or circumstance occurs precisely as well as instances in which the event or circumstance occurs to a close approximation. For example, when used in conjunction with a numerical value, the terms can encompass a range of variation of less than or equal to  $\pm 10\%$  of that numerical value, such as less than or equal to  $\pm 5\%$ , less than or equal to  $\pm 4\%$ , less than or equal to  $\pm 3\%$ , less than or equal to  $\pm 2\%$ , less than or equal to  $\pm 1\%$ , less than or equal to  $\pm 0.5\%$ , less than or equal to  $\pm 0.1\%$ , or less than or equal to  $\pm 0.05\%$ . The term “substantially coplanar” can refer to two surfaces within micrometers of lying along a same plane, such as within  $40\text{ }\mu\text{m}$ , within  $30\text{ }\mu\text{m}$ , within  $20\text{ }\mu\text{m}$ , within  $10\text{ }\mu\text{m}$ , or within  $1\text{ }\mu\text{m}$  of lying along the same plane. For example, “substantially parallel” can refer to a range of angular variation relative to  $0^\circ$  that is less than or equal to  $\pm 10^\circ$ , such as less than or equal to  $\pm 5^\circ$ , less than or equal to  $\pm 4^\circ$ , less than or equal to  $\pm 3^\circ$ , less than or equal to  $\pm 2^\circ$ , less than or equal to  $\pm 1^\circ$ , less than or equal to  $\pm 0.5^\circ$ , less than or equal to  $\pm 0.1^\circ$ , or less than or equal to  $\pm 0.05^\circ$ . For example, “substantially perpendicular” can refer to a range of angular variation relative to  $90^\circ$  that is less than or equal to  $\pm 10^\circ$ , such as less than or equal to  $\pm 5^\circ$ , less than or equal to  $\pm 4^\circ$ , less than or equal to  $\pm 3^\circ$ , less than or equal to  $\pm 2^\circ$ , less than or equal to  $\pm 1^\circ$ , less than or equal to  $\pm 0.5^\circ$ , less than or equal to  $\pm 0.1^\circ$ , or less than or equal to  $\pm 0.05^\circ$ .

[0081] As used herein, the singular terms “a,” “an,” and “the” may include plural referents unless the context clearly dictates otherwise. In the description of some embodiments, a component provided “on” or “over” another component can encompass cases where the former component is directly on (e.g., in physical contact with) the latter component, as well as cases where one or more intervening components are located between the former component and the latter component.

[0082] As used herein, the terms “conductive,” “electrically conductive” and “electrical conductivity” refer to an ability to transport an electric current. Electrically conductive materials typically indicate those materials that exhibit little or no opposition to the flow of an electric current. One

measure of electrical conductivity is Siemens per meter (S/m). Typically, an electrically conductive material is one having a conductivity greater than approximately  $10^4\text{ S/m}$ , such as at least  $10^5\text{ S/m}$  or at least  $10^6\text{ S/m}$ . The electrical conductivity of a material can sometimes vary with temperature. Unless otherwise specified, the electrical conductivity of a material is measured at room temperature.

[0083] While the present disclosure has been described and illustrated with reference to specific embodiments thereof, these descriptions and illustrations are not limiting. It should be understood by those skilled in the art that various changes may be made and equivalents may be substituted without departing from the true spirit and scope of the present disclosure as defined by the appended claims. The illustrations may not necessarily be drawn to scale. There may be distinctions between the artistic renditions in the present disclosure and the actual apparatus due to manufacturing processes and tolerances. There may be other embodiments of the present disclosure which are not specifically illustrated. The specification and the drawings are to be regarded as illustrative rather than restrictive. Modifications may be made to adapt a particular situation, material, composition of matter, method, or process to the objective, spirit and scope of the present disclosure. All such modifications are intended to be within the scope of the claims appended hereto. While the methods disclosed herein have been described with reference to particular operations performed in a particular order, it will be understood that these operations may be combined, sub-divided, or re-ordered to form an equivalent method without departing from the teachings of the present disclosure. Accordingly, unless specifically indicated herein, the order and grouping of the operations are not limitations.

What is claimed is:

1. A semiconductor device package, comprising:

a first substrate having a first surface and a second surface opposite to the first surface;

a second substrate disposed over the first surface of the first substrate; and

an encapsulant covering the first surface and the second surface of the first substrate,

wherein a portion of the second surface of the first substrate is exposed from the encapsulant,

wherein the first substrate has a first lateral surface substantially aligned with a lateral surface of the second substrate.

2. The semiconductor device package of claim 1, further comprising a plurality of conductive elements disposed between the first substrate and the second substrate and electrically connecting the first substrate with the second substrate.

3. The semiconductor device package of claim 2, wherein a first portion of the encapsulant encapsulates the plurality of conductive elements.

4. The semiconductor device package of claim 3, wherein the first portion of the encapsulant includes a first part disposed between adjacent two of the plurality of conductive elements.

5. The semiconductor device package of claim 4, wherein the first part of the first portion of the encapsulant includes a first curved lateral surface and a second curved lateral surface opposite to the first curved lateral surface.

6. The semiconductor device package of claim 5, wherein the first curved lateral surface and the second curved lateral surface are concave toward each other.

7. The semiconductor device package of claim 2, further comprising a plurality of conductive pads disposed adjacent to the second surface of the first substrate, wherein one of the plurality of conductive elements overlaps a respective one of the plurality of conductive pads along a direction substantially perpendicular to the second surface of the first substrate.

8. The semiconductor device package of claim 2, further comprising an electronic component disposed over the second substrate, and vertically overlapping adjacent two of the plurality of conductive elements in the cross-sectional view.

9. A semiconductor device package, comprising:

a first substrate having a first surface and a second surface opposite to the first surface;

a second substrate disposed over the first surface of the first substrate;

an encapsulant covering the first surface and the second surface of the first substrate, wherein the encapsulant has a slanted surface; and

a solder resist layer disposed under the second surface of the first substrate, wherein the slanted surface of the encapsulant connects to a bottom surface of the solder resist layer.

10. The semiconductor device package of claim 9, further comprising a conductive bump disposed adjacent to the second surface of the first substrate, and surrounded by the solder resist layer.

11. The semiconductor device package of claim 10, wherein the conductive bump contacts the solder resist layer, wherein the conductive bump does not contact the encapsulant.

12. The semiconductor device package of claim 10, wherein an elevation of a bottommost point of the conductive bump is lower than an elevation of a bottommost point of the slanted surface of the encapsulant.

13. The semiconductor device package of claim 9, further comprising a conductive bump disposed adjacent to the second surface of the first substrate, wherein the solder resist layer has a lateral surface facing the conductive bump, wherein the lateral surface the solder resist layer is closer to the conductive bump than the slanted surface of the encapsulant is.

14. The semiconductor device package of claim 9, wherein a first portion of the encapsulant is disposed under the second surface of the first substrate and has the slanted surface, wherein the first portion of the encapsulant tapers away from the first substrate.

15. The semiconductor device package of claim 14, further comprising an electronic component disposed over the second substrate, wherein a lateral surface of the electronic component vertically overlaps the first portion of the encapsulant.

16. A semiconductor device package, comprising:

a first substrate having a first surface, a second surface opposite to the first surface and a first lateral surface extending between the first surface and the second surface;

a second substrate disposed over the first substrate; and  
an encapsulant continuously covering the first surface, the first lateral surface and the second surface of the first substrate in a cross-sectional view.

17. The semiconductor device package of claim 16, wherein the encapsulant includes a first portion covering the first surface of the first substrate and a second portion covering the second surface of the first substrate, wherein a vertical thickness of the first portion of the encapsulant is greater than a vertical thickness of the second portion of the encapsulant.

18. The semiconductor device package of claim 16, wherein the second portion of the encapsulant partially covers a solder resist layer disposed on the second surface of the first substrate.

19. The semiconductor device package of claim 18, wherein the solder resist layer surrounds a conductive bump disposed on the second surface of the first substrate, wherein the first portion of the encapsulant surrounds a conductive element disposed on the first surface of the first substrate, wherein a maximum thickness of the conductive bump is less than a maximum thickness of the conductive element.

20. The semiconductor device package of claim 16, wherein the first substrate further has a second lateral surface extending between the first surface and the second surface, wherein the encapsulant further continuously covers the first surface, the second lateral surface and the second surface of the first substrate in the cross-sectional view.

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